PROCEEDINGS OF SPIE

Optical Inspection and Metrology for Non-Optics Industries

Peisen S. Huang Toru Yoshizawa Kevin G. Harding Editors

3–4 August 2009 San Diego, California, United States

Sponsored and Published by SPIE

Volume 7432

The papers included in this volume were part of the technical conference cited on the cover and title page. Papers were selected and subject to review by the editors and conference program committee. Some conference presentations may not be available for publication. The papers published in these proceedings reflect the work and thoughts of the authors and are published herein as submitted. The publisher is not responsible for the validity of the information or for any outcomes resulting from reliance thereon.

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Author(s), "Title of Paper," in *Optical Inspection and Metrology for Non-Optics Industries*, edited by Peisen S. Huang, Toru Yoshizawa, Kevin G. Harding, Proceedings of SPIE Vol. 7432 (SPIE, Bellingham, WA, 2009) Article CID Number.

ISSN 0277-786X ISBN 9780819477224

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445 SPIE.org

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Printed in the United States of America.

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Contents

vii	Conference Committee
ix	Optical design dependence on technology development (Plenary Paper) [7428-01] I. A. Neil, ScotOptix (Switzerland)
	CALIBRATION AND ANALYSIS METHODS I: CALIBRATION
7432 02	Optimal checkerboard selection for structured light system calibration [7432-01] W. Lohry, Y. Xu, S. Zhang, Iowa State Univ. (United States)
7432 03	Measurement accuracy of fringe projection depending on surface normal direction [7432-02] P. Kühmstedt, C. Bräuer-Burchardt, G. Notni, Fraunhofer IOFJena (Germany)
7432 04	High precision calibration method of intrinsic parameters for fish-eye cameras [7432-03] H. Komagata, Saitama Medical Univ. (Japan) and Niigata Univ. (Japan); I. Ishii, Saitama Medical Univ. (Japan); H. Makino, Niigata Univ. (Japan); A. Takahashi, Nagaoka National College of Technology (Japan); D. Wakatsuki, Tsukuba Univ. of Technology (Japan)
7432 05	New calibration technique for a novel stereo camera [7432-04] X. Tu, M. Subbarao, SUNY, Stony Brook (United States)
7432 06	3D cutting tool inspection system and its key technologies [7432-05] X. M. Du, T. Chen, X. J. Zou, GE Global Research (China); K. G. Harding, GE Global Research (United States)
7432 07	3D measurement method based on wavelet transform by using SEM [7432-06] Y. Arai, M. Ando, Kansai Univ. (Japan); S. Yokozeki, Jyouko Applied Optics Lab. (Japan)
	CALIBRATION AND ANALYSIS METHODS II: DATA ANALYSIS
7432 08	A fringe period unwrapping technique for digital fringe profilometry based on spatial shift estimation [7432-07] P. Cao, J. Xi, J. F. Chicharo, Y. Yu, Univ. of Wollongong (Australia)
7432 09	Shift-variant image deblurring for machine vision: one-dimensional blur [7432-08] M. Subbarao, Y. Kang, X. Tu, SUNY, Stony Brook (United States)
7432 0A	Automatic inspection of textured surfaces by support vector machines [7432-09] S. Jahanbin, A. C. Bovik, The Univ. of Texas at Austin (United States); E. Pérez, D. Nair, National Instruments Corp. (United States)
7432 OB	Stokes parameters of reflected and scattered light by a rough surface [7432-10] L. Jin, Univ. of Yamanashi (Japan); K. Takizawa, Seikei Univ. (Japan)

7432 0C	Data processing and parameter extraction for cutting tool inspection [7432-11] T. Chen, X. M. Du, J. M. Zheng, GE Global Research (China); K. G. Harding, GE Global Research (United States)
	OPTICAL METROLOGY AND 3D APPLICATIONS I
7432 0D	In-process inspection of internal threads of machined automotive parts [7432-12] H. Zhang, R. Katz, Univ. of Michigan (United States); J. S. Agapiou, General Motors Corp. (United States)
7432 OE	Measure of roughness of paper using speckle [7432-13] A. Pino, J. Pladellorens, Politècnic Univ. de Catalunya (Spain)
7432 OF	A novel method for overlay measurement by scatterometry [7432-14] WT. Hsu, YS. Ku, DM. Shyu, Industrial Technology Research Institute (Taiwan)
	OPTICAL METROLOGY AND 3D APPLICATIONS II
7432 OH	In situ analysis of fruit anthocyanins by means of total internal reflectance, continuous wave and time-resolved spectroscopy [7432-16] M. Zude, Leibniz Institute for Agricultural Engineering Potsdam-Bornim (Germany); L. Spinelli, Politecnico di Milano (Italy); C. Dosche, Univ. of Potsdam (Germany); A. Torricelli, Instituto di Fotonica e nanotecnologie, IFN-CNR, Politecnico di Milano (Italy)
7432 OJ	Inner surface profile measurement of a hydrodynamic bearing by an oblique incidence and two-wavelength interferometer [7432-18] O. Sasaki, R. Yamamura, K. Yokoyama, T. Suzuki, Niigata Univ. (Japan)
7432 OK	Digital processing of an interferometric velocimeter for ballistic shock measurement [7432-19] P. Kumar, A. Thomas, R. S. Weis, T. J. Tayag, Texas Christian Univ. (United States)
7432 OL	In-plane and out-of-plane deformation and vibration measurement using an optomechanical image derotator [7432-20] M. Rahlves, S. Mirzaei, T. Fahlbusch, E. Reithmeier, Leibniz Univ. Hannover (Germany)
	3D METHODS I: STRUCTURED LIGHT AND PHASE METHODS
7432 ON	Digital multiple wavelength phase shifting algorithm [7432-22] S. Zhang, Iowa State Univ. (United States)
7432 00	Continuous scanning phase measurement for high immunity to vibration [7432-23] J. Park, J. You, SW. Kim, Korea Advanced Institute of Science and Technology (Korea, Republic of)
7432 OP	Three-dimensional profilometry system incorporating a MEMS scanner [7432-24] T. Yoshizawa, T. Wakayama, Saitama Medical Univ. (Japan)

7432 OS	Comparison of projection means for structured light systems [7432-27] K. Harding, GE Global Research (United States)
	3D METHODS II: SPECKLE, HOLOGRAPHIC, AND DYNAMIC METHODS
7432 OT	Microscopic TV sherography for microsystems characterization [7432-28] U. P. Kumar, N. K. Mohan, M. P. Kothiyal, Indian Institute of Technology Madras (India)
7432 0V	3D inspection microscope using holographic primary objective [7432-30] T. D. Ditto, DeWitt LLC (United States); J. Knapp, S. Biro, Aspex, Inc. (United States)
7432 OW	Dual mode interferometer for measuring dynamic displacement of specular and diffuse components [7432-31] M. North Morris, T. Horner, M. Naradikian, J. Shiefman, 4D Technology Corp. (United States)
	3D METHODS III: OTHER METHODS INCLUDING COLOR, STEREO, AND FOCUS
7432 0X	Combined stereovision and phase shifting method: use of a color visibility-modulated fringe pattern [7432-32] X. Han, P. Huang, Stony Brook Univ. (United States); Z. Deng, L. Xu, Nokia Research Ctr. (China)
7432 OY	Pixel synchronous measurement of object shape and colour [7432-33] J. Siepmann, M. Heinze, P. Kühmstedt, G. Notni, Fraunhofer IOF Jena (Germany)
7432 OZ	Chromatic confocal spectral interferometry for technical surface characterization [7432-34] W. Lyda, D. Fleischle, T. Haist, W. Osten, Univ. Stuttgart (Germany)
7432 10	Three-dimensional profilometry based on focus method by projecting LC grating pattern [7432-35] Y. Otani, F. Kobayashi, Y. Mizutani, Tokyo Univ. of Agriculture and Technology (Japan); T. Yoshizawa, Saitama Medical Univ. (Japan)
7432 11	A portable 3D shape measurement system based on the combined stereovision and phase shifting method [7432-36] X. Han, P. Huang, Stony Brook Univ. (United States); Z. Deng, L. Xu, Nokia Research Ctr. (China)
7432 12	Real-time 3D part metrology using polarization rotation [7432-37] G. Abramovich, K. Harding, V. Paruchuru, S. Manickam, C. Nafis, J. Czechowski, GE Global Research (United States); A. Vemury, U.S. Dept. of Homeland Security (United States)
7432 13	Laser Doppler distance sensors using phase and frequency evaluation [7432-38] J. W. Czarske, T. Pfister, P. Günther, L. Büttner, Dresden Univ. of Technology (Germany)

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7432 14	Research of the chromaticity coordinates and color spectrum calibration using tristimulus sensors and eigenspectrum method [7432-39] OY. Mang, TW. Huang, YF. Hsieh, National Central Univ. (Taiwan); YT. Kuob, National Chiao-Ting Univ. (Taiwan) and Jen-Teh Junior College of Medicine (Taiwan)
7432 16	Iterative estimation of the topography by means of structured light [7432-42] A. Martínez García, J. A. Rayas-Alvarez, Ctr. de Investigaciones en Óptica A.C. (Mexico); H. J. Puga Soberanes, Instituto Tecnológico de León (Mexico); K. Genovese, Univ. degli Studi della Basilicata (Italy)
7432 17	Multi-channel liquid crystal cell parameter measurement technique [7432-43] CS. Liu, KP. Chuang, YS. Lin, MY. Zhuang, CJ. Chiang, Industrial Technology Research Institute (Taiwan)
7432 18	Method to measure frequency change of tunable laser based on Jamin shearing interferometer [7432-44] L. Wang, L. Liu, J. Sun, Y. Zhou, Z. Luan, D. Liu, Shanghai Institute of Optics and Fine Mechanics (China)
7432 1A	Measurement of frequency swept linearly with Fabry-Perot fiber interferometer [7432-46] Z. Luan, N. Xu, D. Liu, Y. Zhou, L. Liu, Shanghai Institute of Optics and Fine Mechanics (China)
7432 1B	Computation of crack tip elastic strain intensity factor in mode I by electronic speckle pattern interferometry [7432-47] J. Parra Michel, A. Martínez, J. A. Rayas, Ctr. de Investigaciones en Óptica, A.C. (Mexico)
7432 1C	Three-dimensional embedded defect detection and localization in a semi-transparent medium [7432-48] G. Abramovich, C. Nafis, Y. Williams, K. Harding, E. Tkaczyk, GE Global Research (United States)
	Author Index

Conference Committee

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1 Calibration and Analysis Methods I: Calibration Peisen S. Huang, Stony Brook University (United States)

- 2 Calibration and Analysis Methods II: Data Analysis Song Zhang, Iowa State University (United States)
- Optical Metrology and 3D Applications I
 Toru Yoshizawa, Saitama Medical University (Japan)
- Optical Metrology and 3D Applications II
 Peisen S. Huang, Stony Brook University (United States)
- 3D Methods I: Structured Light and Phase Methods **Peter Kuehmstedt**, Fraunhofer-Institut für Angewandte Optik und Feinmechanik (Germany)
- 6 3D Methods II: Speckle, Holographic, and Dynamic Methods **Kevin Harding**, GE Global Research (United States)
- 3D Methods III: Other Methods Including Color, Stereo, and Focus Seung-Woo Kim, Korea Advanced Institute of Science and Technology (Korea, Republic of)